

# Assessment of Industry Research Priorities for Intelligent Sensors and Control



*Ya-Shian Li-Baboud*, Julien Amelot,  
Julien Le Guen (NIST)

Alan Weber, Paul McGuire  
(Alan Weber & Associates)

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# Outline

- Vision and Objectives
- Challenges and Perspectives
- NIST Sensor Network Testbed
- Research Opportunities
- Acknowledgements



# Initial Vision

## *Seamless integration and communication*

- Sensors and control enjoy the same "plug and play" paradigm as consumer electronics
- Leverage "cloud computing"
  - Enable complex data analysis over distributed systems
  - Factory distributed systems support a fundamental set of services for infrastructure and application development
  - Manufacturing equipment provides high quality data, at right time, all the time
  - Future standards support development of a cloud computing platform to enable rapid data, software, and hardware integration
- Factory information and control systems respond and adapt to the real-time needs of Advanced Process Control (APC) and Predictive and Preventive Maintenance (PPM)



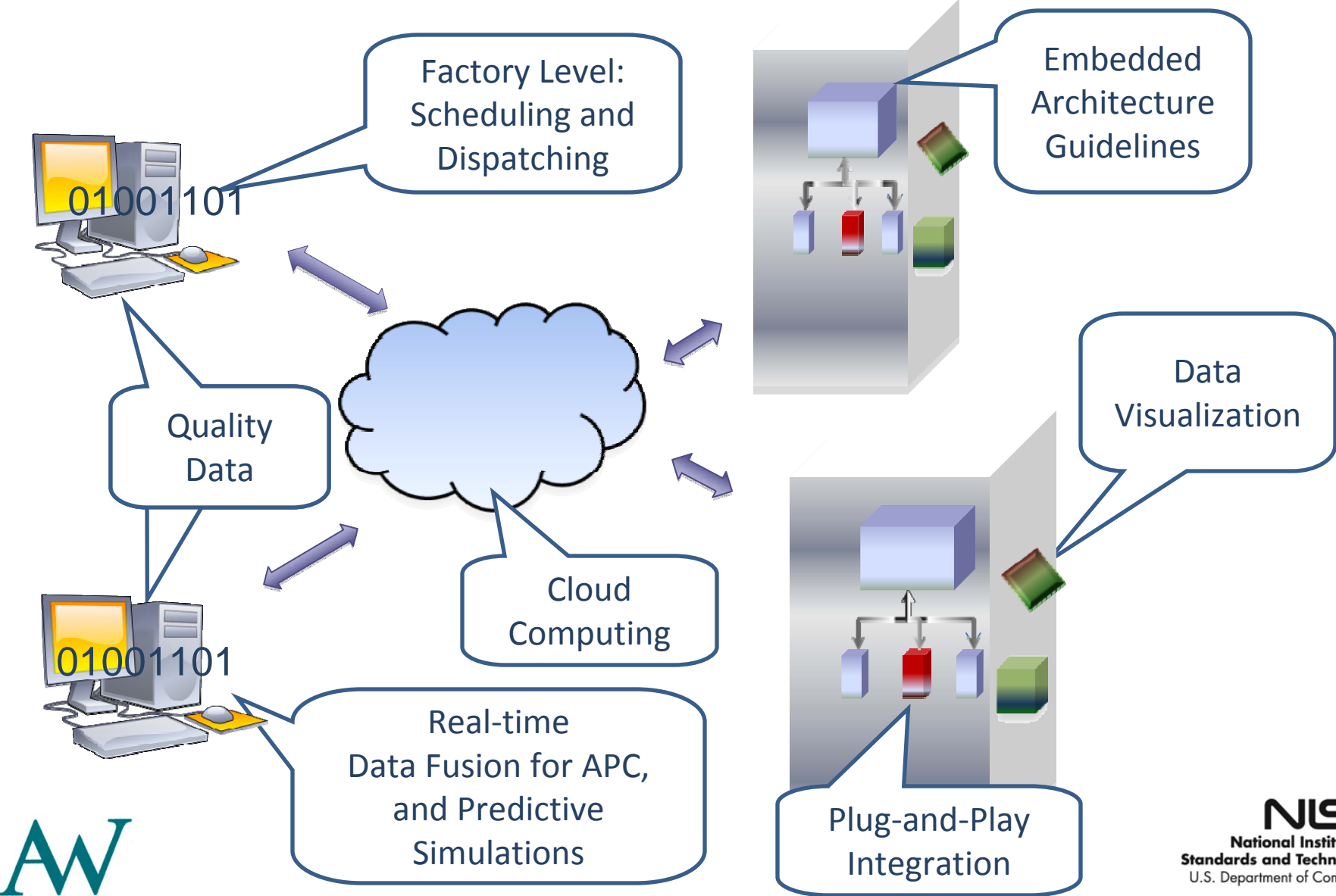
# Objectives

## *Sensors and control study*

- Understand factory automation challenges
  - Factory/equipment cost, time, and technology constraints
  - Continuous improvement of cost, cycle time and yield
  - Next-Generation Factory (300mm Prime), Photovoltaic manufacturing (PV)
- Identify research needs and gaps
  - Innovation areas
  - Current and upcoming areas of research
  - How research can be used to address current challenges
- Call for Participation
  - Avoid re-inventing the wheel
  - Enable effective technology transfer
  - Focus on infrastructure, pre-competitive challenges



# Potential Factory Improvements



# Challenges

## *Technical*



- Physical integration (mounting, signal access) of a sensor is often more difficult than the logical (commands, data) integration
- Knowing whether or not a sensor is providing an accurate measurement (may be the sensor, NOT the process, that's drifting)
- New processes require better data accessibility to understand correlations among parameters and process yield
- Time synchronization of raw data, especially between the separate subsystems within a single tool
- Drawing the lines in a hierarchical control scheme, given the technology to support broadly distributed control
- Building factory-level integrated control systems that can seamlessly incorporate sensor-level information

# Challenges

## *Commercial*



- Semiconductor manufacturers and equipment suppliers both feel that detailed equipment/process data is their IP
- Overcoming the "do-it-yourself" mentality with respect to equipment control system design requires more thorough life-cycle analysis
- Add-on sensor projects are heavily ROI driven
  - It's often difficult to get the needed data
  - Equipment suppliers to an established fab have little motivation to change embedded control systems for one-off sensor projects
- Equipment suppliers require more understanding of what data would be necessary and what justifies the need for higher data collection frequency to benefit the process in order to justify ROI

# Challenges

## *Structural*

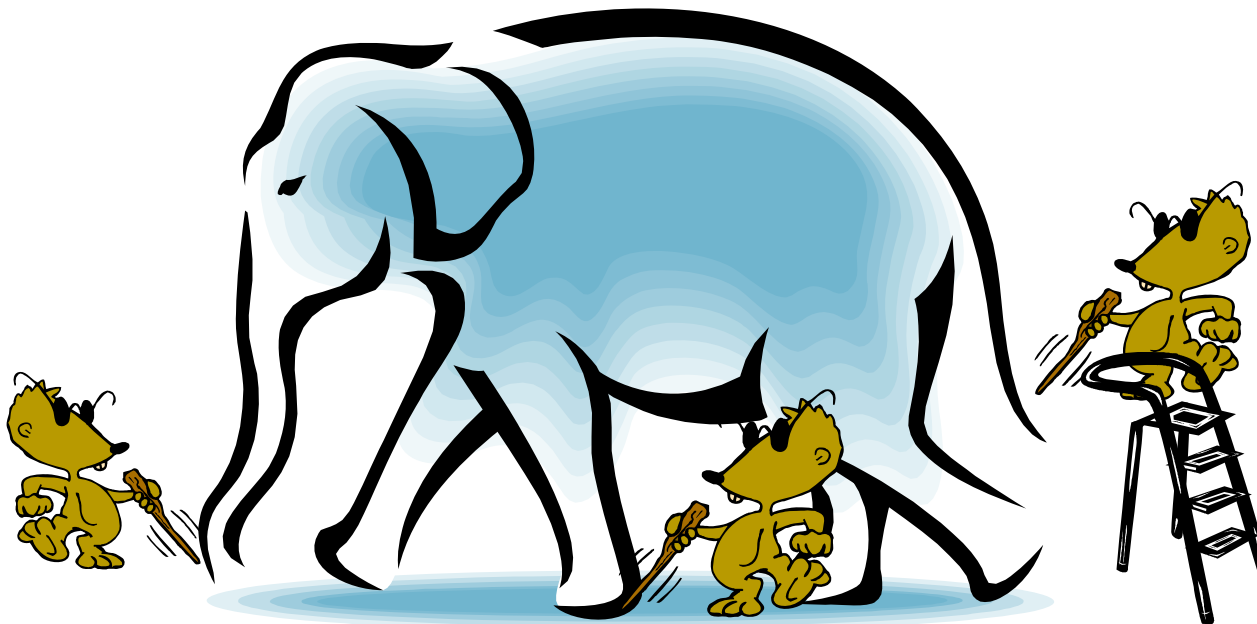


- The independence of semiconductor equipment suppliers works against the objective of having standards-based embedded control systems across the industry
- Developing a new sensor and related control scheme is often [at least] a three-party problem
  - Access to a production fab and its data often the biggest issue
- Standards development process
  - Needs to maintain the pace of technology evolution
  - Should include full validation and adoption support
- There is still a lot to be learned from other industries
  - Even in a "moving target" rapid technology evolution environment



# Perspectives

- The problems and opportunities are very different depending on a company's perspective
  - Semiconductor manufacturers
  - Equipment suppliers
  - Sensor, subsystem, and software suppliers



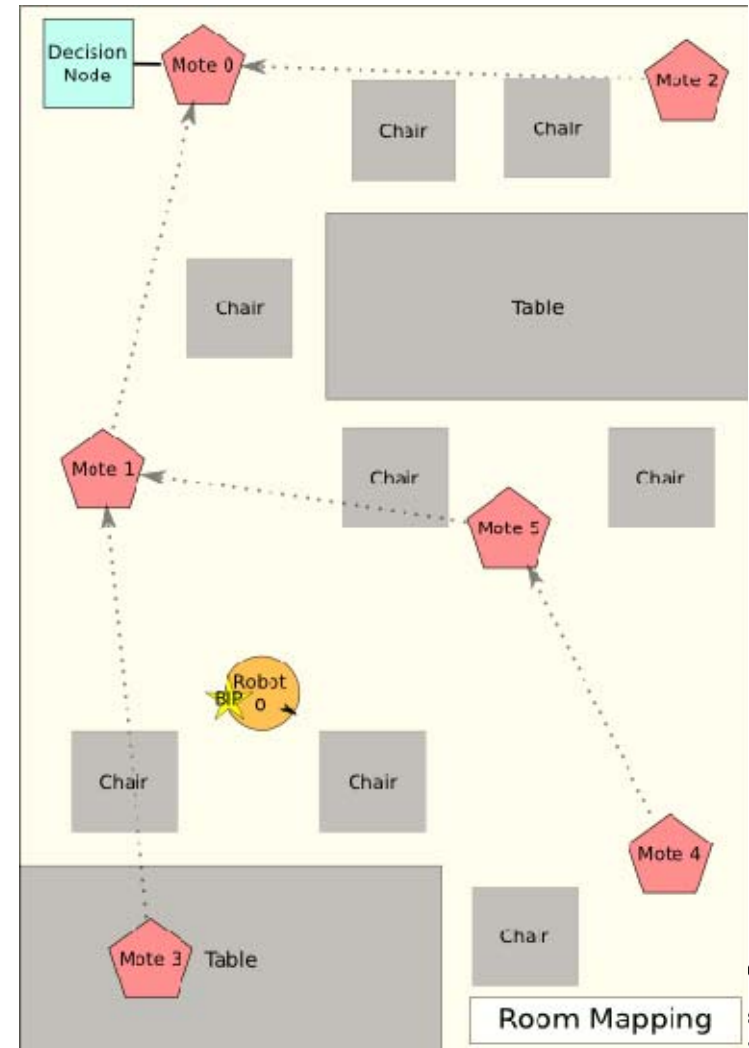
# NIST Sensor Network Testbed Goals

- Characterize sensor network data issues
  - Data sources
  - Data communication
  - Data processing (filtering, linearization, compression)
  - Data analysis (dynamic summary statistics in real-time)
- Explore high-risk concepts and technologies
  - Time synchronization of embedded systems (reference implementation)
  - Sensor mote technologies
  - Adaptive learning, self-aware systems
- Prototypes and recommended practices
  - Example "best practice" for embedded control system architecture
  - Configurable reference RF chamber and/or process simulation tools for new sensor validation
  - Pre-standards development and demonstration
  - Standards adoption support (e.g. guidelines for equipment emulators)

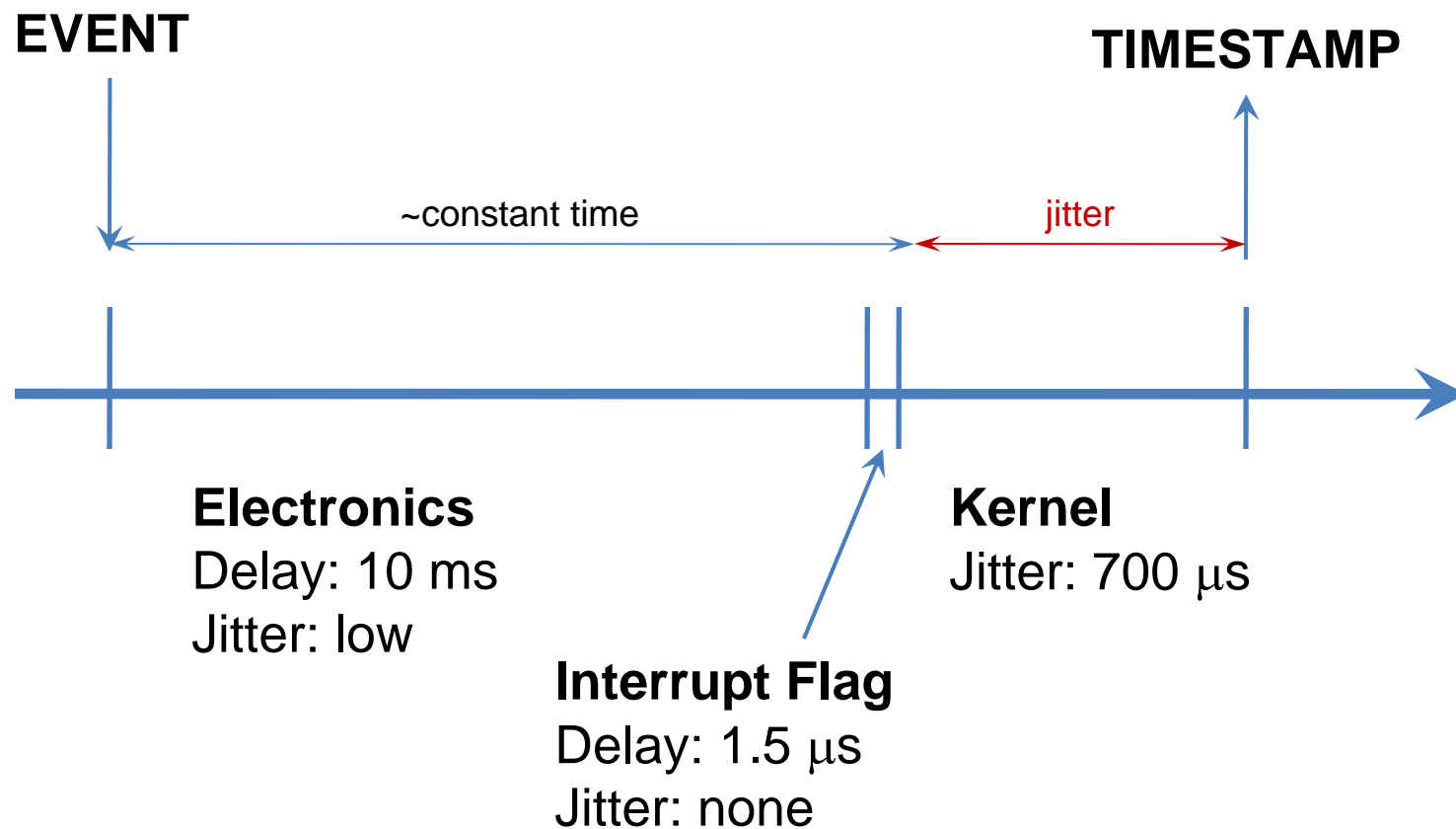


# Sensor Network Testbed Setup

- Initial abstraction of issues
  - Time synchronization
  - Sensor time-stamping
  - Data filtering
  - Data fusion
- Components
  - Decision node (data fusion and analysis)
  - Sensor motes (data source)
  - Mobile robots (control)



# Characterization of data time-stamping



# Research Opportunities

- Sensor Integration
  - Self-description and discovery
  - Interface development
  - Dynamic behavior and required interactions
- Data Acquisition Systems
  - Real-time acquisition
  - Software data filtering techniques
  - Novel user interfaces and visualization
  - Data mining and correlation
  - Data fusion techniques (time-stamping)



# Research Opportunities

- Communications
  - Network characterization and performance
  - Wired and wireless
- Equipment Control Systems
  - Finer granularities of control
  - Distributed processing
  - Real-time decision making and adaptive control
  - Improving current programming models (concurrency)
- Standards Adoption
  - Rapid prototyping before and during standards development
  - Guidelines, reference implementation, and compliance testing



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